

[0050] (Amended) Referring to Fig. 10, an add-on system detector is generally indicated by reference numeral 500. OPV probe 20 may directly replace a standard overfill probe with no modification to the tank or system. However, the probes that the OPV probe 20 replace only output a permit waveform or no waveform. Thus, a prior art on-board monitor 502 will only detect a permit signal or no signal from OPV probe 20. If excessive pressure or vacuum is detected, the OPV probe 20 outputs an over-pressure or over-vacuum waveform instead of a dry waveform, or no waveform. Since these very low frequency waveforms are not detected by existing on-board monitors 502 or terminal racks, they are treated the same as if no waveform was generated. This will cause the pumps to shut down at a loading terminal. Thus, the OPV probe 20 may be used with legacy systems that do not support the over-pressure and/or over-vacuum signals from the probe.

REMARKS

In response to the office action dated May 25, 2005, applicant has amended paragraphs 0024, 0026, 0031, 0032, 0039, 0041, 0043, and 0050 to correct errors or ambiguities identified by the examiner.

Additionally, substitute drawing sheets are also enclosed for correction or clarification made to Figs. 2, 6 and 8d.

Accordingly, the present application should now be passed to issuance.

Respectfully submitted,



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